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# Electrodeposition of copper applied to the manufacture of seamless SRF cavities

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### **Outline**

1. Current production process/problematic

2.Technical proposal

3.Samples characterization

4. Dislocation density by EBSD

5.Towards first 1.3 GHz cavity

6.Optimization of the process

## **Production of copper SRF substrates**

**STANDARD METHOD - Half cell spinning and welding** 



Half cell spinning

Welding

#### **Possible defects**





Weld porosities

- Presence of porosities along the junction caused by the welding process
- Copper sheets can contain defects

## **Production of copper SRF substrates**

**SEAMLESS METHOD - Cell spinning around mandrel** 



Cell spinning

Cut-offs welding

#### Additional possible defects

– – – Beam axis



Mandrel footprint Cu cracking

- Mandrel footprint can appear on the copper surface
- Large deformation introduced in the process can lead to high cracking

# **Cu electroforming - approach**

The cavity is produced by copper electroforming around a sacrificial aluminium mandrel which is precoated with a copper thin film.



- Robust and leak-tight seamless cavity
- Challenges
- Smooth inner surface state
- High copper purity and conductivity

# **Cu electroforming - approach**

• Study the properties of electroformed copper in flat samples



• Study the robustness of the assembly in prepared cavity test dummies



DC plating



Pulsed plating (PP)

Dummy2

# **Electroformed copper properties**

• UTS/ Young modulus



Roughness



# **Electroformed copper properties**

#### Residual Resistivity Ratio





- DC matches Cu OFE specs after thermal treatment
- PP can lead to very high RRR without thermal treatment

- Thermal conductivity
- Samples measured after deposition
- Pulse plated sample conductivity 5 times larger than OFE spec.

![](_page_7_Figure_9.jpeg)

- After 2h at 400°C
- Triplicated conductivity for DC plated after thermal treatment

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# **Electron back scatter diffraction (EBSD)**

#### Cu OFE by Spinning and Electro-Hydraulic Forming (EHF)

![](_page_9_Picture_2.jpeg)

![](_page_9_Picture_3.jpeg)

#### Iris samples

![](_page_9_Figure_5.jpeg)

E. García-Tabarés et al, Electron Backscatter Diffraction meeting. Plymouth, April 2018.

- To accommodate plastic deformation, the material generates dislocations, which disturb the structure of the lattice and lead to local misorientations.
- Study local misorentation by measuring the kernel average misorientation (KAM).
- This criteria displays small orientation gradients, highlighting areas of high Geometrically Necessary Dislocations (GND) density.

![](_page_9_Figure_10.jpeg)

### **EBSD** and dislocation density

<KAM>

7

6

5.5

5

4 3.5 3 2.5 2 1.5 1 0.5 0

4.5

6.5

![](_page_10_Picture_1.jpeg)

Dummy2 **Pulse plated cavity** 

![](_page_10_Figure_4.jpeg)

![](_page_10_Figure_5.jpeg)

#### Equator samples

![](_page_10_Picture_7.jpeg)

Horizontal plane  $200\,\mu m$ 

![](_page_10_Picture_9.jpeg)

## **EBSD** and dislocation density

![](_page_11_Figure_1.jpeg)

#### Spinning vs Electro-Hydraulic Forming

- Low dislocation density in electroformed copper.
- Similar GND density than reference copper OFE before machining.

![](_page_11_Figure_5.jpeg)

![](_page_11_Figure_6.jpeg)

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## **1.3 GHz Mandrel production**

How to produce such an aluminium mandrel?

#### Machined from bulk aluminium

![](_page_13_Picture_3.jpeg)

Mandrel cell turning

Mechanical finishing

Tubes welding/machining

For the moment: Standard machining finishing

![](_page_13_Picture_8.jpeg)

![](_page_13_Picture_9.jpeg)

![](_page_14_Picture_1.jpeg)

![](_page_14_Picture_2.jpeg)

![](_page_14_Figure_3.jpeg)

Cathode (reduction): Cu<sup>2+</sup> + 2e<sup>-</sup> → Cu

Anode (oxidation):  $Cu \rightarrow Cu^{2+} + 2^{e-}$ 

![](_page_15_Picture_1.jpeg)

336 hours of plating (Pulse plating + DC plating)

![](_page_16_Figure_1.jpeg)

- 2 mm plating at the iris
- 6.4 mm plating at the equator

![](_page_16_Picture_4.jpeg)

![](_page_17_Picture_1.jpeg)

Aluminum dissolution NaOH 5M

Surface preparation: SUBU

![](_page_17_Picture_4.jpeg)

![](_page_18_Figure_1.jpeg)

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Electroforming process

## **COMSOL** simulations for optimization

![](_page_20_Figure_1.jpeg)

# Design of secondary anodes and masking

• Solution for uniformity: Secondary anodes positioned at the iris to promote plating, mask at the equator to reduce the deposition.

![](_page_21_Picture_2.jpeg)

## **Design of secondary anodes and masking**

![](_page_22_Figure_1.jpeg)

## Implementation of support

![](_page_23_Picture_1.jpeg)

![](_page_23_Picture_2.jpeg)

Fabrication

![](_page_23_Picture_4.jpeg)

![](_page_23_Picture_5.jpeg)

![](_page_23_Picture_6.jpeg)

![](_page_23_Picture_7.jpeg)

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Copper PVD process

# **Optimization of Cu coating process**

- **HiPIMS sputtering:** high peak power densities in short pulses.
- The sputtered material is highly ionized and is accelerated towards substrate thanks to the positive pulse.
- High-quality dense homogeneous films

#### DCMS

![](_page_25_Figure_5.jpeg)

#### High Power Impulse Magnetron Sputtering

![](_page_25_Figure_7.jpeg)

#### **HiPIMS + PP**

![](_page_25_Figure_9.jpeg)

- Very compact coatings.
- No porosities.

## Conclusions

![](_page_26_Picture_1.jpeg)

• Cavity lifecycle (production-coating-rinsing-testing-stripping) feasibility has been demonstrated with the electroformed 1.3 GHz cavity.

![](_page_26_Picture_3.jpeg)

The main drawback of the electroforming approach is the non-uniform thickness distribution along the cavity.

Solution: secondary anodes and masking to the cavity. The plating time will be reduced by half.

![](_page_26_Picture_6.jpeg)

- The Cu PVD layer was optimized by applying HiPIMS.
- Very low dislocation density on the iris and equator of electroformed cavity.

### **Perspectives**

- 1.3 GHz cavity production and validation of the secondary anodes support.
- Optimal surface preparation technique before coating.
- Nb thin film coating using best recipe and RF testing.

- Different mandrels surface state: electroforming on polished mandrels.
  - Diamond turning finishing
  - Electro-polishing of the aluminium mandrels

### Thank you for your attention!